

Title (en)

APPARATUS AND METHOD FOR TRANSPORTING SUBSTRATES

Title (de)

VORRICHTUNG UND VERFAHREN ZUM TRANSPORT VON SUBSTRATEN

Title (fr)

DISPOSITIF ET PROCÉDÉ DE TRANSPORT DE SUBSTRATS

Publication

EP 2534676 A1 20121219 (DE)

Application

EP 10751653 A 20100902

Priority

- DE 102010008233 A 20100211
- EP 2010062915 W 20100902

Abstract (en)

[origin: WO2011098157A1] An apparatus for transporting silicon wafers in a horizontal transporting direction into a printing device has two transporting units, which each have a traversing device and a holding means thereon. At least two transporting units each with a holding means are provided, wherein the traversing devices of said units run next to each other along the transporting direction. The holding means are each formed and arranged in such a way that an unloaded holding means has space to pass by a holding means loaded with a silicon wafer. The traversing devices are rails and the holding means are carriages mounted thereon.

IPC 8 full level

H01L 21/677 (2006.01); **H01L 21/687** (2006.01)

CPC (source: EP US)

B05C 13/02 (2013.01 - US); **H01L 21/67748** (2013.01 - EP US); **H01L 21/67784** (2013.01 - EP US); **H01L 21/68714** (2013.01 - EP US); **H01L 21/68764** (2013.01 - EP US)

Citation (search report)

See references of WO 2011098157A1

Citation (examination)

US 2008014058 A1 20080117 - HONGKHAM STEVE S [US], et al

Designated contracting state (EPC)

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DOCDB simple family (application)

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